


FORM PTO 1449 (modified)  U.S. DEPARTMENT OF COMMERCE PATENT AND TRADEMARK OFFICE  LIST OF REFERENCES CITED BY APPLICANT(S) (Use several sheets if necessary)			ATTY DOCKET NO. <b>00862.022336.1</b>		APPLICATION NO. <b>10/644,032</b>		
<div style="border: 2px solid black; border-radius: 50%; padding: 10px; display: inline-block;">             PTE JC139              JAN 09 2004              PATENT &amp; TRADEMARK OFFICE           </div>			APPLICANTS <b>KAZUTAKA YANAGITA ET AL.</b>				
			FILING DATE <b>August 20, 2003</b>		GROUP <b>3752</b>		
U.S. PATENT DOCUMENTS							
*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE	
y	5,458,755	10/17/95	Fujiyama et al.	204	224 R		
y	5,371,037	12/6/94	Yonehara	437	86		
y	5,856,229	1/5/99	Sakuguchi et al.	483	406		
y	5,811,348	9/22/98	Matsushita et al.	438	455		
y	6,107,213	8/22/00	Tayanaka	438	762		
y	5,863,830	1/26/99	Bruel et al.	438	478		
y	5,360,748	11/1/94	Nadahara et al.	437	11		
y	6,186,193B1	2/13/01	Phallen et al.	141	83		
y	6,391,743B1	5/21/02	Iwane et al.	438	458		
FOREIGN PATENT DOCUMENTS							
		DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT
y	WO	98/52216	11/19/98	PCT	X		
y	EP	0 867 917	9/30/98	Europe			
y		7-302889	11/14/95	Japan			Abstract
y		11-45840	2/16/99	Japan			Abstract
y		5-21338	1/29/93	Japan			Abstract
OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)							
y		R.P. Holmstrom et al., "Complete dielectric isolation by highly selective and self-stopping formation of oxidized porous silicon", Appl. Phys. Lett 42(4), pp. 386-388, 15 February 1983.					
y		A. Uhlir, Jr., "Electrolytic Shaping of Germanium and Silicon", The Bell System Technical Journal, Volume XXXV 1956, pp. 333-347.					
y		K. Nagano et al., "Oxidized Porous Silicon and It's Application", IEICE, vol. 79, pp. 49-54, SSD79-9549, 1979.					
y		T. Unagami, "Formation Mechanism of Porous Silicon Layer by Anodization in HF Solution", Journal of the Electrochemical Society, Vol. 127, No. 2, pp. 476-483, February 1980					
EXAMINER				DATE CONSIDERED <u>5/23/05</u>			

\*EXAMINER: Initial if reference considered, whether or not citation is in conformance with MPEP 609; Draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.

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PATENT AND TRADEMARK OFFICELIST OF REFERENCES CITED BY APPLICANT(S)  
(Use several sheets if necessary)ATTY DOCKET NO.  
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KAZUTAKA YANAGITA ET AL.FILING DATE  
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3752

## U.S. PATENT DOCUMENTS

*EXAMINER INITIAL	DOCUMENT NUMBER	DATE	NAME	CLASS	SUBCLASS	FILING DATE IF APPROPRIATE
	6,427,747	08/06/02	Omi et al.	156	584	
	6,418,999	07/16/02	Yanagita et al.	156	584	
	6,436,226	08/20/02	Omi et al.	156	344	
	6,427,748	08/06/02	Yanagita et al.	156	584	
	6,350,703	02/26/02	Sakaguchi et al.	438	766	
	6,382,292	05/07/02	Ohmi et al.	156	584	
	6,468,923	10/22/02	Yonehara et al.	438	761	
	6,448,155	09/10/02	Iwasaki et al.	438	464	
	6,313,014	11/06/01	Sakaguchi et al.	438	475	
	20010038153	11/08/01	Sakaguchi et al.	—	—	
20020045237	04/18/02	Yanagita et al.	—	—		

## FOREIGN PATENT DOCUMENTS

DOCUMENT NUMBER	DATE	COUNTRY	CLASS	SUBCLASS	TRANSLATION YES/NO/ OR ABSTRACT

OTHER DOCUMENT(S) (Including Author, Title, Date, Pertinent Pages, Etc.)


EXAMINER

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5/23/05

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